



TDK-Lambda Corporation  
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## EU DECLARATION OF CONFORMITY

### RWS1000B Series

We, TDK-Lambda Corporation, of Shibaura Renasite Tower, 3-9-1 Shibaura, Minato-ku, Tokyo, Japan, declare under our sole responsibility that the TDK-Lambda power supplies, as detailed on the attached products covered sheets, complies with the provisions of the following European Directives and is eligible to bear the CE mark:

Low Voltage	Directive 2014/35/EU
EMC	Directive 2014/30/EU
RoHS 2	Directive 2011/65/EU

Assurance of conformance of the described product with the provisions of the stated EC Directive is given through compliance to the following standards:

Electrical Safety (LVD)	EN 60950-1: 2006 + A2: 2013
Electromagnetic Compatibility (EMC)	EN 61000-6-2: 2005 EN 61000-6-4: 2007 + A1: 2011 EN 61000-3-2: 2014 EN 55011: 2009 + A1: 2010 - Class B

**Note:** The EMC performance of a component power supply will be affected by the final installation, compliance to the stated EMC standards and conformance to the EMC Directive must be confirmed after installation by the final equipment manufacturer. For guidance with respect to test conditions please visit our website at [emea.tdk-lambda.com/EMC\\_guidance](http://emea.tdk-lambda.com/EMC_guidance) or contact your local TDK-Lambda sales office.

Our representative in the EU is TDK-Lambda Germany GmbH, located at Karl-Bold-Str. 40, 77855 Achern, Germany.

Name of Authorized Signatory:	Christopher Haas
Signature of Authorized Signatory:	
Position of Authorized Signatory:	Technical & Quality Manager, TDK-Lambda Germany GmbH
Date:	15 <sup>th</sup> June 2018
Date when first CE marked:	19 <sup>th</sup> December 2016
Place where signed:	Achern, Germany

The products covered by this declaration are:

RWS1000B-12, RWS1000B-15, RWS1000B-24, RWS1000B-36, RWS1000B-48

May be followed by suffix abcde where  
a = /, b = R or S, c = CO2, d = FO, e is RF and abcde may be blank.  
In addition, there is RFO combination R and FO